

LIFTING DEVICE, SUBSTRATE PROCESSING APPARATUS PROVIDED WITH
LIFTING DEVICE, AND METHOD OF CONVEYING UNIT

ABSTRACT OF THE DISCLOSURE

[Problem] An object of the present invention is to facilitate height level adjustment of a substrate processing apparatus regardless of size thereof.

[Means for Solving] A lifting device 630b includes: a lifting mechanism 640 that is provided between at least one of a plurality of units of a substrate processing apparatus and an installation surface of the unit, and that adjusts height of the at least one unit with respect to the installation surface; and an adjustment member 660 that is provided with an extended section 664 extended from the lifting mechanism 640, and that is capable of operating the lifting mechanism 640 through the extended section 664.

[Selected Drawings] FIG. 6